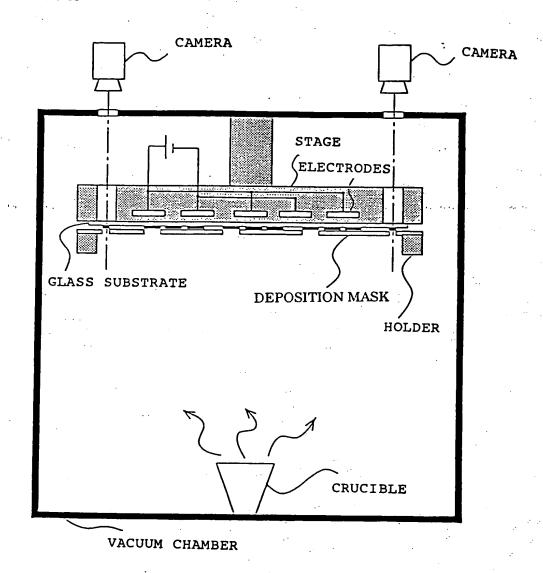
Title: MASK VAPOR DEPOSITION METHOD, MASK VAPOR DEPOSITION SYSTEM, MASK,
- PROCESS FOR MANUFACTURING MASK, ...
Inventor(s): Mitsuro ATOBE (et al)
Atty. Ref.: 9319K-000606

FIG. 1



Inventor(s): Mitsuro ATOBE (et al) Atty. Ref.: 9319K-000606

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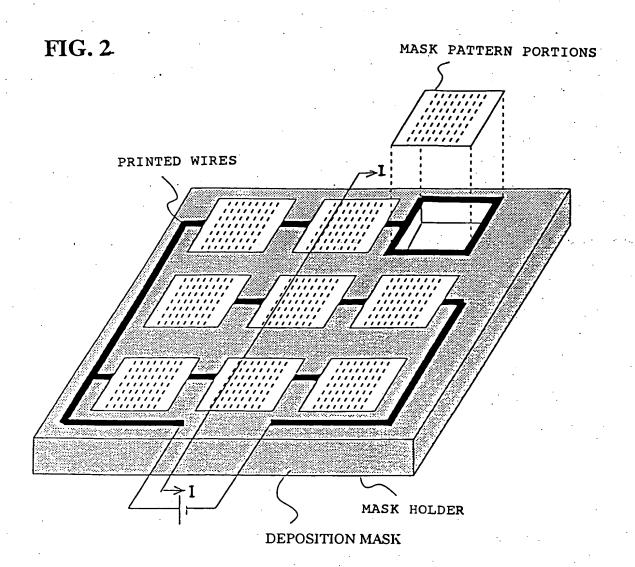
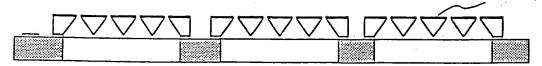


FIG. 3

INSULATING LAYER



Title: MASK VAPOR DEPOSITION METHOD, MASK VAPOR DEPOSITION SYSTEM, MASK, PROCESS FOR MANUFACTURING MASK, ...
Inventor(s): Mitsuro ATOBE (et al)
Atty. Ref.: 9319K-000606

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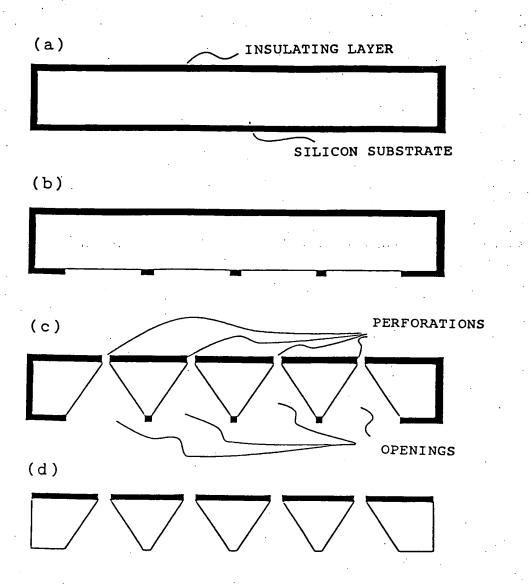


FIG. 4

Inventor(s): Mitsuro ATOBE (et al) Atty. Ref.: 9319K-000606

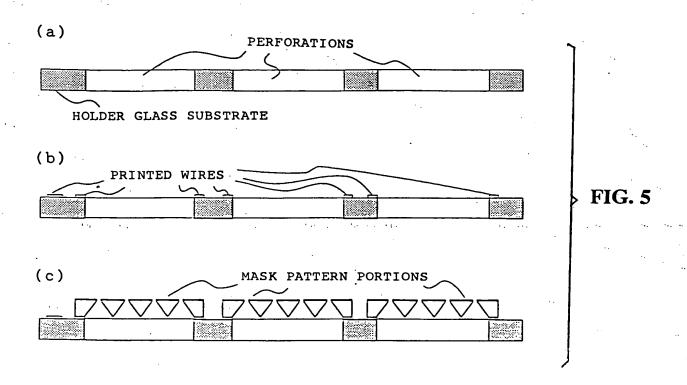
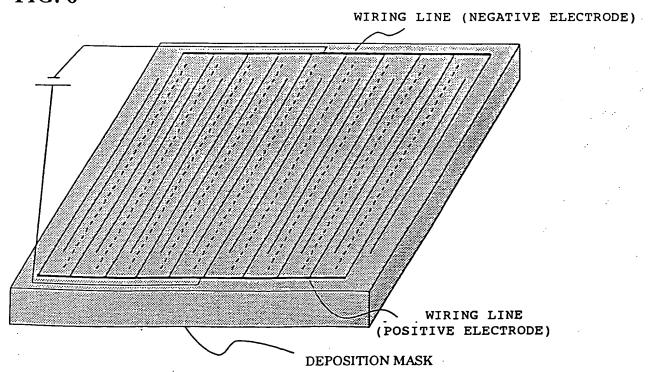
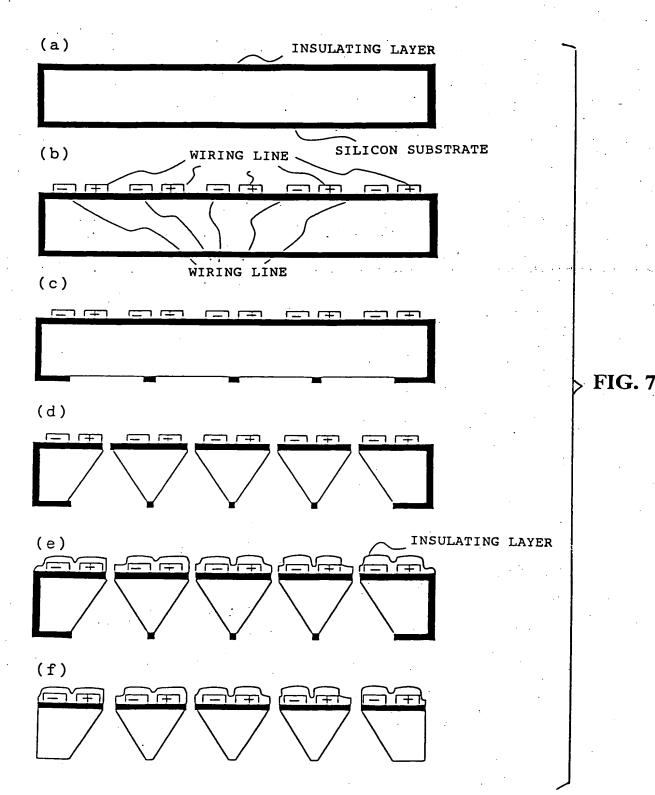


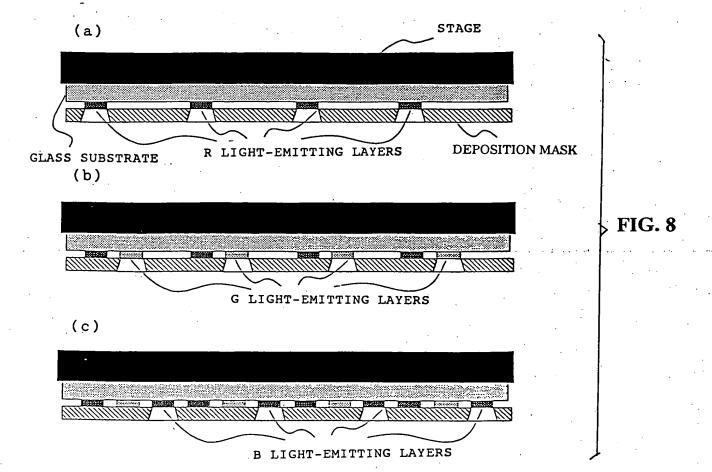
FIG. 6



Title: MASK VAPOR DEPOSITION METHOD, MASK VAPOR DEPOSITION SYSTEM, MASK, PROCESS FOR MANUFACTURING MASK, ...
Inventor(s): Mitsuro ATOBE (et al)
Atty. Ref.: 9319K-000606



Inventor(s): Mitsuro ATOBE (et al) Atty. Ref.: 9319K-000606



Inventor(s): Mitsuro ATOBE (et al) Atty. Ref.: 9319K-000606

FIG. 9A

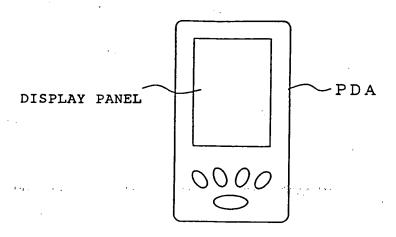


FIG. 9B

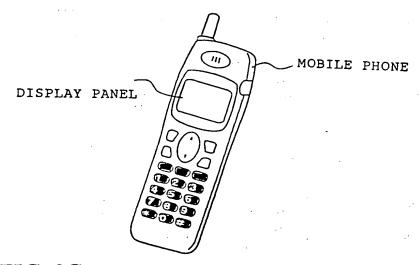


FIG. 9C

